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**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231, on August 12, 2002.

Signature:

*Rebecca A Baumark*

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**PATENT**

Attorney Docket No. NTI-024

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application	)	<u>PATENT APPLICATION</u>
	)	
Inventor(s): Fang-Cheng Chang et al.	)	
	)	Art Unit: 2623
Application No.: 09/941,453	)	
	)	Examiner: J. Mancuso
Filed: 08/28/2001	)	
	)	
Title System And Method For Identifying Dummy	)	
Features On A Mask Layer	)	
	)	
	)	

**INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97**

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

Listed below or on an attached Form PTO-1449 is information known to applicant(s). A copy of each listed publication and U.S. and foreign patent, except for pending U.S. applications, is being submitted herewith, along with a concise explanation of information in a foreign language, if any, pursuant to 37 C.F.R. §1.97-1.98.

Applicants respectfully request that the listed information be considered by the Examiner and be made of record in the above-identified application. If form PTO-1449 is enclosed, the Examiner is requested to initial and return it in accordance with MPEP § 609.

This statement is not intended to represent that a search has been made or that the information cited in the statement is, or is considered to be, material to patentability as defined in 37 C.F.R. § 1.56.

This statement qualifies under 37 C.F.R. § 1.97, subsection (b) because (check all that apply):

(1) It is being filed within 3 months of the application filing date and is other than a continued prosecution application under § 1.53(d)  
-- OR --

(2) It is being filed within 3 months of entry of a national stage  
-- OR --

(3) It is being filed before the mail date of the first Office Action on the merits.  
-- OR --

(4) It is being filed before the mailing of a first Office Action after the filing of a request for continued examination under § 1.114

37 C.F.R. § 1.97(c). If this statement is being filed after the period specified in § 1.97(b), but before the mailing date of the earlier of a final office action under § 1.113, a notice of allowance under § 1.311, or an action that otherwise closes prosecution in the application, then:

a certification as specified in § 1.97(e) is provided below; or

a fee of \$180.00 as set forth in § 1.17(p) is authorized below, enclosed, or included with the payment of other papers filed together with this statement.

37 C.F.R. § 1.97(d). If this statement is being filed after the period specified in § 1.97(c), but on or before payment of the issue fee, then:

A. a certification as specified in § 1.97(e) is completed below; and

B. a fee of \$180.00 as set forth in § 1.17(p) is authorized below, enclosed, or included with the payment of other papers filed together with this statement.

*Fee Authorization.* The Commissioner is hereby authorized to charge any additional fees or credit any overpayment associated with this communication to Deposit Account No. 50-0574 (Docket No. NTI-024).

Dated: Aug 12, 2012

Respectfully submitted,

BEVER, HOFFMAN & HARMS, LLP

By:   
Jeanette S. Harms, Reg. No. 35,537

Telephone: (408) 451-5907  
Customer No. 29477



SHEET 1 of 3

**INFORMATION DISCLOSURE  
CITATION**  
**PTO-1449**

Atty. Docket No. **NTI-024** Serial No. **09/941,453-6364**  
Applicant **CHANG, Fang-Cheng**  
Filing Date **8/28/2001** Group **Not Yet Assigned**

**U.S. PATENT DOCUMENTS**

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	6,016,357	1/18/2000	Neary, et al.	382	144	6/16/1997
	6,023,328	2/8/2000	Pierrat	356	237.4	2/23/1998
	6,076,465	6/20/2000	Vacca, et al.	101	481	9/19/1997
	6,091,845	7/18/2000	Pierrat, et al.	382	144	2/24/1998
	6,272,236	8/7/2001	Pierrat, et al.	382	144	7/18/2000
	6,334,209 B1	12/25/2001	Hashimoto, et al.	716	21	9/2/1999
	2002/0019729 A1	2/14/2002	Chang, et al.	703	6	8/7/1998

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EXAMINER: \_\_\_\_\_

Date Considered: \_\_\_\_\_

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP § 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



SHEET 2 of 3

**INFORMATION DISCLOSURE  
CITATION**  
**PTO-1449**

Atty. Docket No.	Serial No.
NTI-024	09/941,453-6364
Applicant	
CHANG, Fang-Cheng	
Filing Date	Group
8/28/2001	Not Yet Assigned

**FOREIGN PATENT DOCUMENTS**

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
	WO 97/13370	4/10/1997	WO			<input type="checkbox"/>	<input type="checkbox"/>
	WO 98/20327	5/14/1998	WO			<input type="checkbox"/>	<input type="checkbox"/>
	WO 98/45685	10/15/1998	WO			<input type="checkbox"/>	<input type="checkbox"/>
	WO 99/38002	7/29/1999	WO			<input type="checkbox"/>	<input type="checkbox"/>
	WO 99/56113	11/4/1999	WO	AUG 20 2002		<input type="checkbox"/>	<input type="checkbox"/>
	WO 99/59200	11/18/1999	WO	Technology Center 2600		<input type="checkbox"/>	<input type="checkbox"/>
	WO 99/67626	12/29/1999	WO			<input type="checkbox"/>	<input type="checkbox"/>
	WO 99/14706 A2/A3	3/25/1999	WO			<input type="checkbox"/>	<input type="checkbox"/>

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SHEET 3 of 3

<b>INFORMATION DISCLOSURE CITATION</b>  <b>PTO-1449</b>	<b>Atty. Docket No.</b> NTI-024	<b>Serial No.</b> 09/941,453-6364
	<b>Applicant</b> CHANG, Fang-Cheng	
	<b>Filing Date</b> 8/28/2001	<b>Group</b> Not Yet Assigned

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**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)**

EXAMINER'S INITIALS	CITATION
	Spence, C., et al., "Detection of 60(degree) Phase Defects on Alternating PSMs", Advanced Micro Devices, KLA-Tencor, DuPont RTC (2 pages).
	Ogawa, K., et al., "Phase Defect Inspection by Differential Interference", Lasertec Corporation (12 pages).
	Socha, R., et al., "Printability of Phase-Shift Defects Using a Perturbational Model", Univ. of California Berkeley, Sematech (11 pages).
	Fiekowsky, P., "The End of Thresholds: Subwavelength Optical Linewidth Measurement Using the Flux-Area Technique", Automated Visual Inspection (6 pages).
	Watanabe, H., et al., "Detection and Printability of Shifter Defects in Phase-Shifting Masks", Japanese Journal of Applied Physics, Vol. 30, No. 11B, pp. 3016-3020, November 1991.
	Hosono, K., et al., "A Novel Architecture for High Speed Dual Image Generation of Pattern Data for Phase Shifting Reticle Inspection", SPIE - Integrated Circuit Metrology, Inspection, and Process Control VI, Vol. 1673, pp. 229-235 (1992).
	Ohtsuka, H., et al., "Evaluation of Repair Phase and Size Tolerance for a Phase-Shift Mask", J. Vac. Sci. Technol. B, Vol. 11, No. 6, pp. 2665-2668, November/December 1993.
	Reynolds, J., "Elusive Mask Defects: Reflectivity Variations", Solid State Technology, pp. 75-76, March 1995.
	Kusunose, H., et al., "Direct Phase-Shift Measurement with Transmitted Deep-UV Illumination", SPIE, Vol. 2793, pp. 251-260 (1996).
	Fiekowsky, P., et al., "Defect Printability Measurement on the KLA-351: Correlation to Defect Sizing Using the AVI Metrology System", SPIE 19th Annual BACUS Symposium on Photomask Technology and Management Conference, pp. 1-6, September 1999.
	Tejnil, E., et al., "Option for At-Wavelength Inspection of Patterned Extreme Ultraviolet Lithography Masks", SPIE Bacus '99, pp. 1-12 (1999).
	Hemar, S., et al., "Finding Killer CD Variations by Full-Reticle CD Mapping", Microlithography World, pp. 4, 6, 8 & 10 (Summer 2000).

EXAMINER: \_\_\_\_\_

Date Considered: \_\_\_\_\_

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP § 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.